

| Form PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF ART CITED BY APPLICANT (Use several sheets if necessary) | | | | ATTY. DOCKET NO. MI22-1533 | | SERIAL NO. 09/754,926 | |
|---|----|-----------------|---|--------------------------------|-------|--------------------------|-------------------------------|
| | | | | APPLICANT Kie Y. Ahn et al. | | | |
| | | | | FILING DATE January 4, 2001 | | GROUP 2813 | |
| U.S. PATENT DOCUMENTS | | | | | | | |
| *Examiner Initial | | Document Number | Date | Name | Class | Subclass | Filing Date If Appropriate |
| | AA | | | | | | |
| FOREIGN PATENT DOCUMENTS | | | | | | | |
| | | Document Number | Date | Country | Class | Subclass | Translation |
| | AB | | | | | | Yes No |
| OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | | |
| | AC | | "High Quality Ta _x O _y Gate Dielectrics with T _x < 10 Å"; H.F. Luan, S.J. Lee, C.H. Lee, S.C. Song, Y.L. Mao, Y. Senzaki, D. Roberts, and D.L. Kwong, IEDM, pp. 141-144, 1999. | | | | |
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| EK | AD | | Article: "High-K Dielectrics for Giga-Scale CMOS and Non-Volatile Memory Technology"; L. Manchanda, G. Alers, and J.P. Han, March 15, 2000. | | | | |
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| EK | AE | | Article: "Application of Al _x O _y Grown by Atomic Layer Deposition to DRAM and FeRAM"; C.T. Kim, C. Lim, K.M. Kim, M.S. Kim, H.K. Jang, Y.S. Yu and J.S. Roh, pg. 316, March 13, 2000. | | | | |
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| | AG | | "Effect of Plasma Activation on the Phase Transformations of Aluminum Oxide"; O. Zywicki, G. Hoetzsch, Surface & Coatings Technology 76-77, 1995; pp. 754-762 | | | | |
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| | AJ | | | | | | |
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| EXAMINER <i>Eric Kifer</i> | | | DATE CONSIDERED <i>5/8/02</i> | | | | |
| *EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. | | | | | | | |